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Micromachined Thermal Flow Sensors—A Review

Jonathan T. W. Kuo [1], Lawrence Yu [1] and Ellis Meng [1,2,*]

[1] Department of Biomedical Engineering, University of Southern California, Los Angeles, CA 90089, USA; E-Mails: jonathan.kuo@usc.edu (J.T.W.K.); lawrency@usc.edu (L.Y.)

[2] Ming Hsieh Department of Electrical Engineering, University of Southern California, Los Angeles, CA 90089, USA

* Author to whom correspondence should be addressed; E-Mail: ellis.meng@usc.edu; Tel.: +1-213-740-6952; Fax: +1-213-821-3897.

Due to an oversight by the author, in the research article [1], on page 553, in Section 2.1.2 "For example, a simple one-dimensional model of a calorimetric sensor on silicon substrate heater temperature is [27]", the reference "[27]" is replaced by "[43]".

In addition, on page 554, the equation "$\gamma_{1,2} = \frac{v \pm \sqrt{v^2 + 16a^{2K}/\delta^2}}{4aK}$" is corrected as:

$$\gamma_{1,2} = \frac{v \pm \sqrt{v^2 + 16ka^2/\delta^2}}{4ak}$$

We apologize for any inconvenience this may have caused.

References

1. Kuo, J.T.W.; Yu, L.; Meng, E. Micromachined Thermal Flow Sensors—A Review. *Micromachines* **2012**, *3*, 550–573.

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